## **ACKNOWLEDGEMENT RECEIPT**

Electronic Version 1.1

Stylesheet Version v1.1.1

Title of Invention

## HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER

Submision Type: Information Disclosure

Statement

**Application Number:** 

10/680783

EFS ID: 99001

Server Response:

Confirmation Code	Message
	Submission was successfully submitted - Even if Informational or Warning Messages appear below, please do not resubmit this application
ICON1	5859
	Eer assistance with e-filing a patent application, contact the Patent Electronic Business Center: Toll-Free Number:1(866) 217-9197 Website: http://www.uspto.gov/ebc/

First Named Applicant: William Jones

Attorney Docket Number:

Timestamp: 2005-12-13 19:34:13 EDT

From: us

File Listing:

Doc. Name	File Name	Size (Bytes)	Date
			Produced
			(yyyymmdd)
us-ids	SSI04001-usidst.xml	1797	2005-12-13
us-ids	us-ids.dtd	7763	2005-12-13
us-ids	us-ids.xsl	12026	2005-12-13
package-data	SSI04001-pkda.xml	1706	2005-12-13
package-data	package-data.dtd	27025	2005-12-13
package-data	us-package-data.xsl	19263	2005-12-13
Total files size		69580	

Message Digest: c041ae85ffb0abfec7a3fc50e0d005c32753932d

Digital Certificate Holder C

Name:

cn=Thomas B.

Haverstock,ou=Registered Attorneys,ou=Patent and

Trademark

Office,ou=Department of

Commerce,o=U.S. Government,c=US